

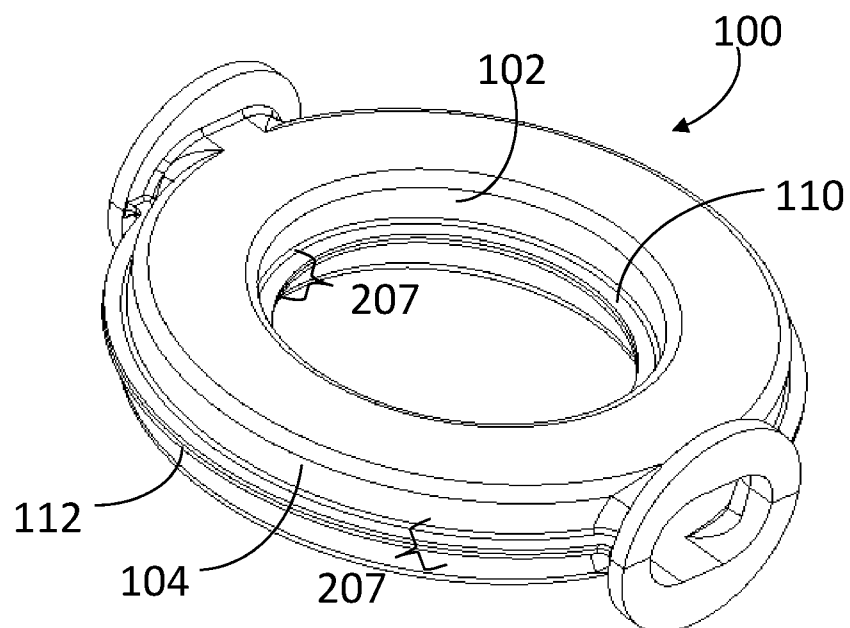


FIG. 1

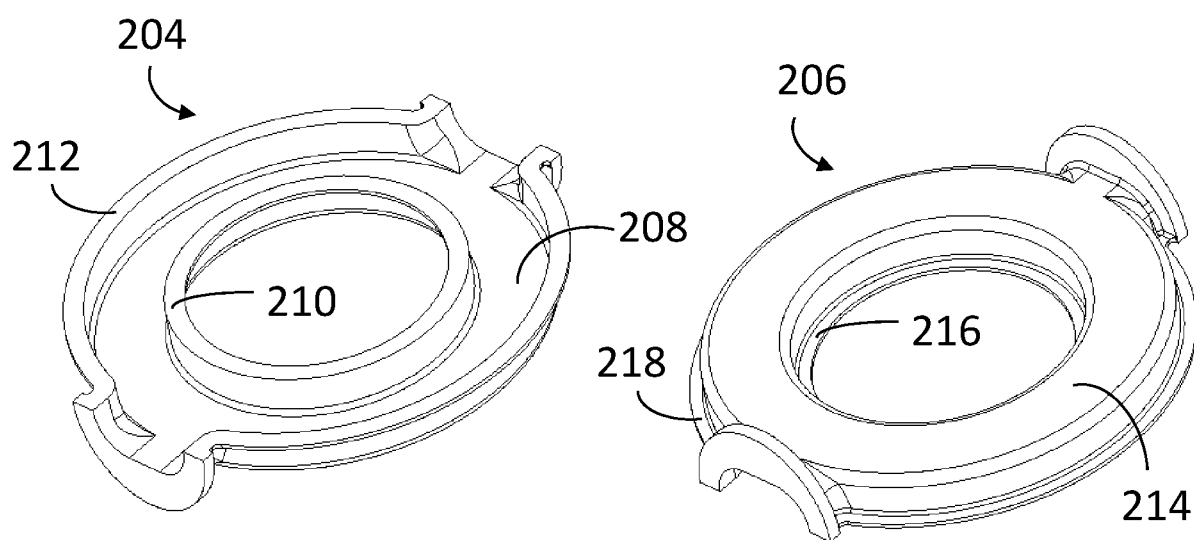


FIG. 2

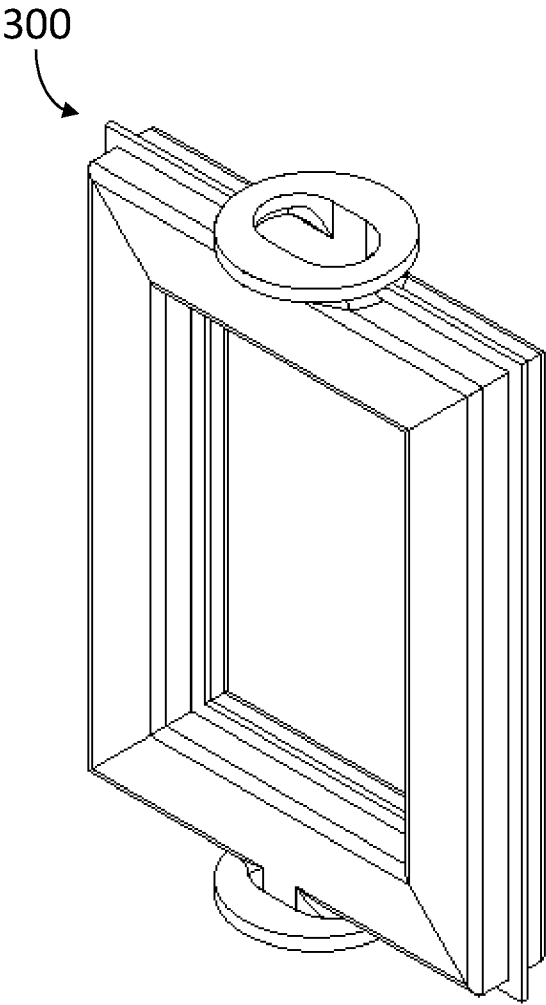


FIG. 3

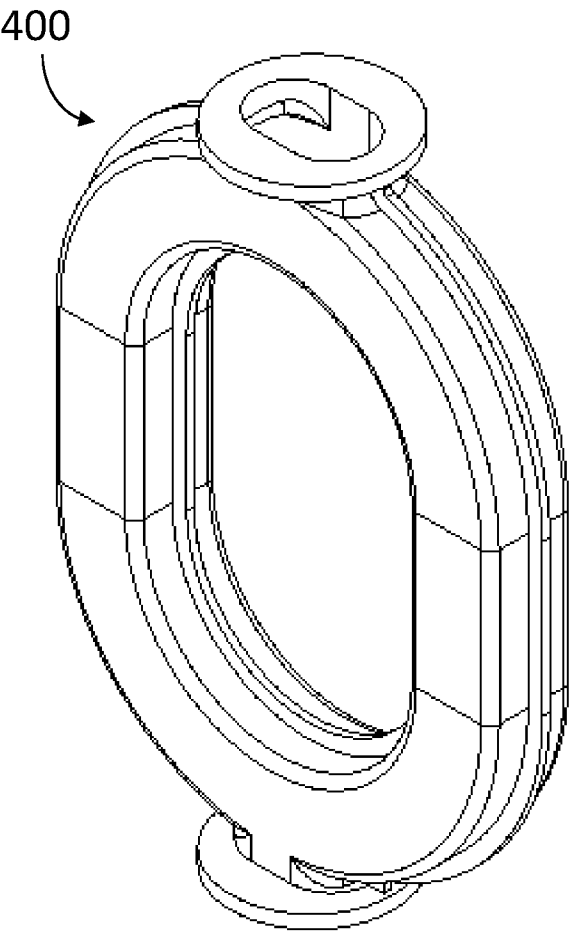
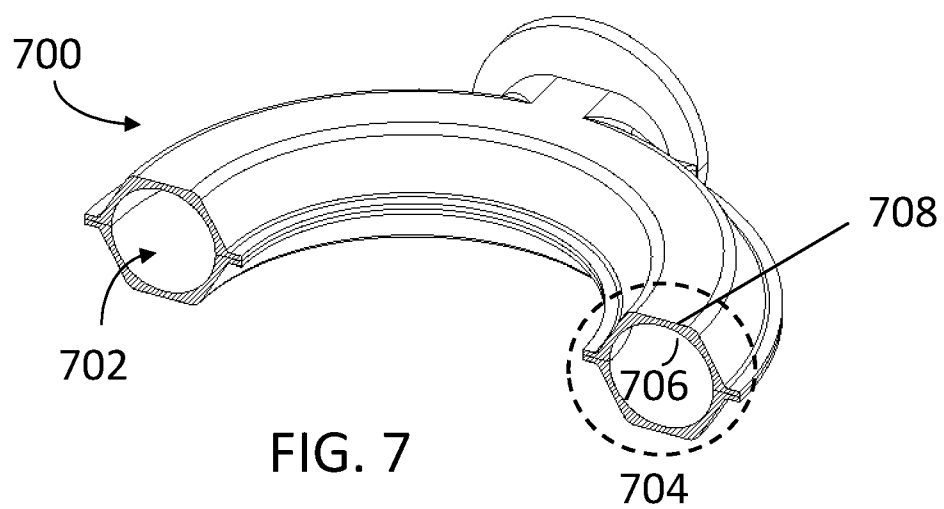
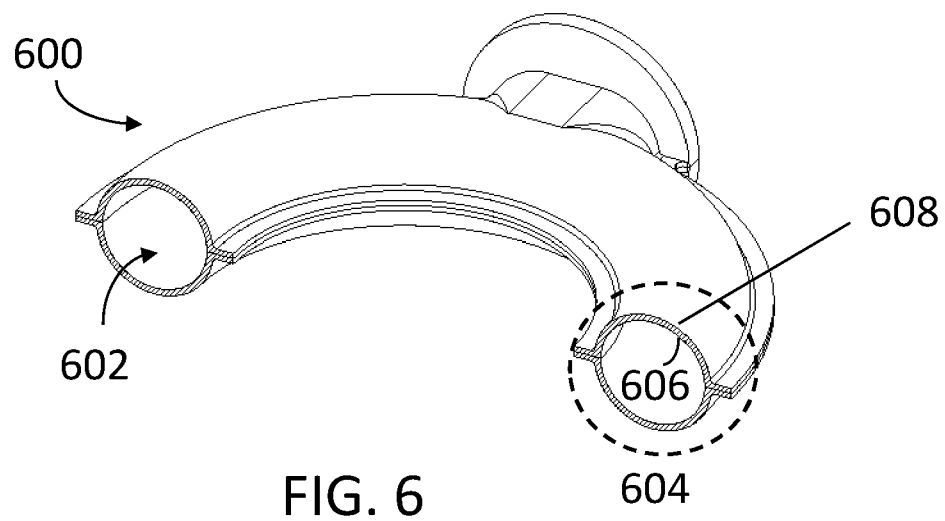
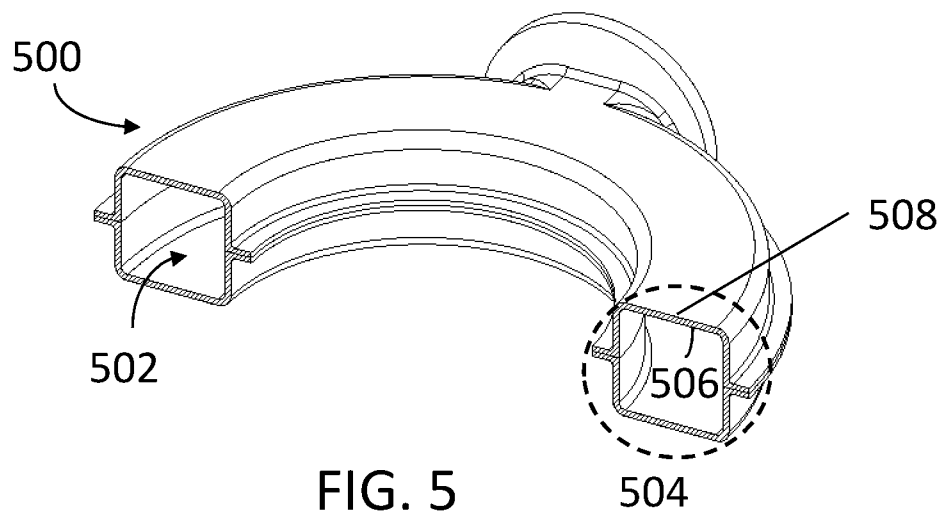


FIG. 4



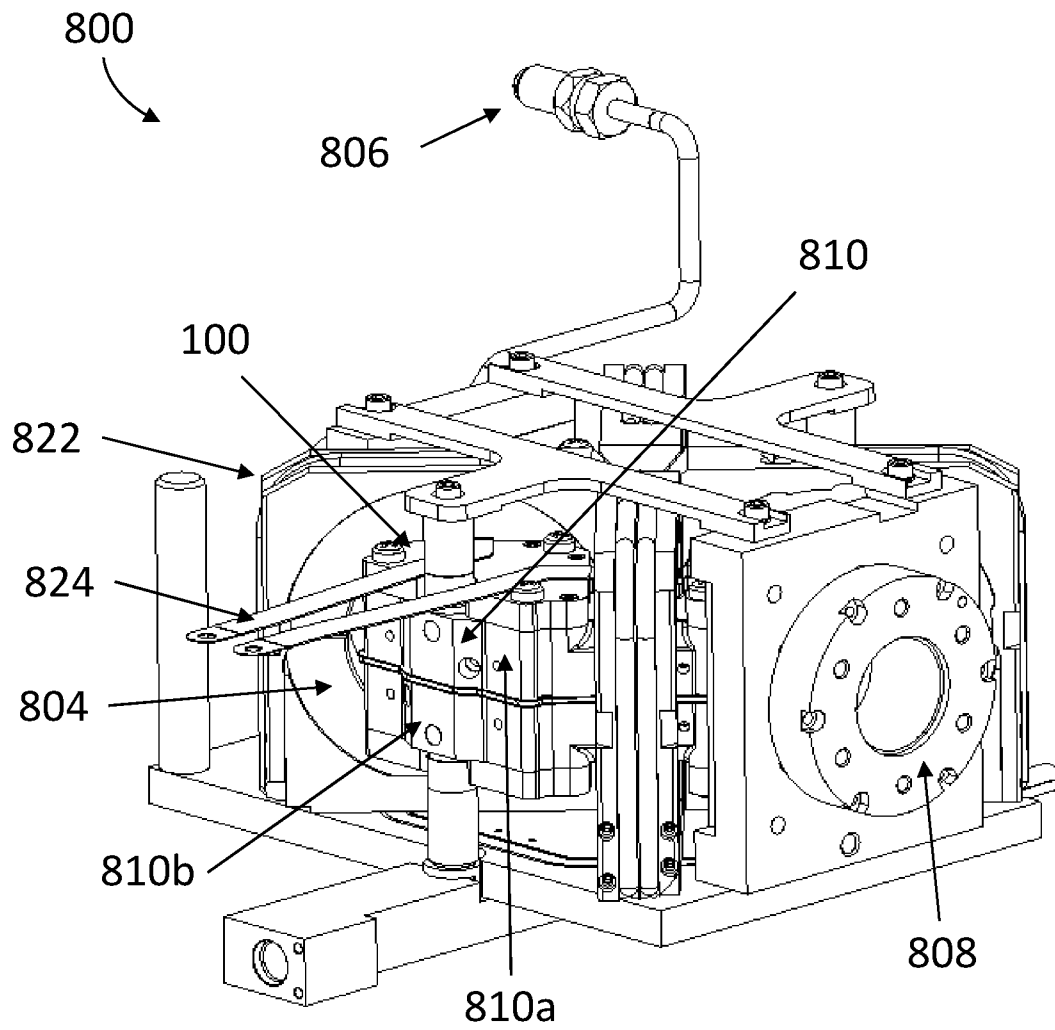


FIG. 8A

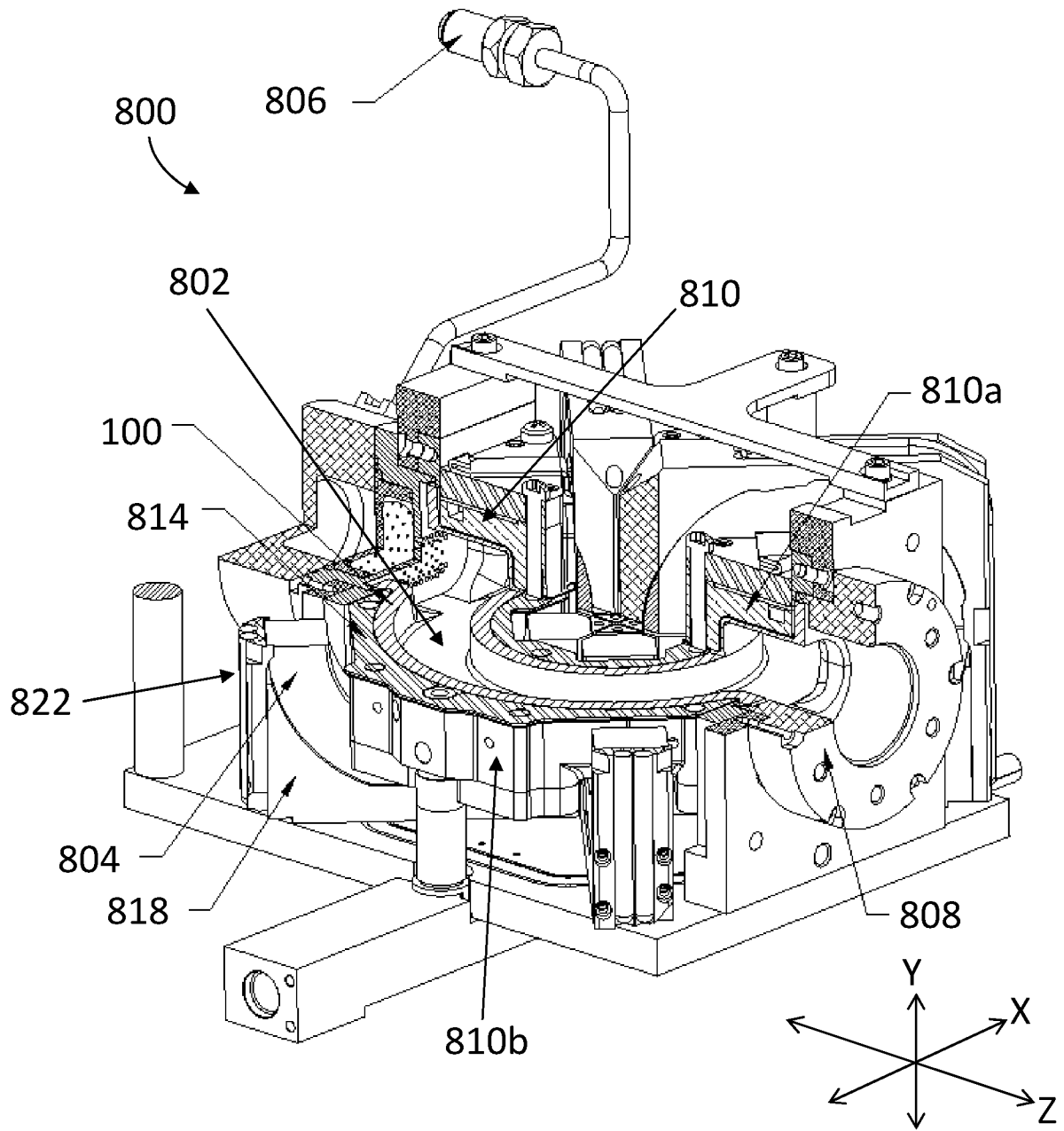


FIG. 8B

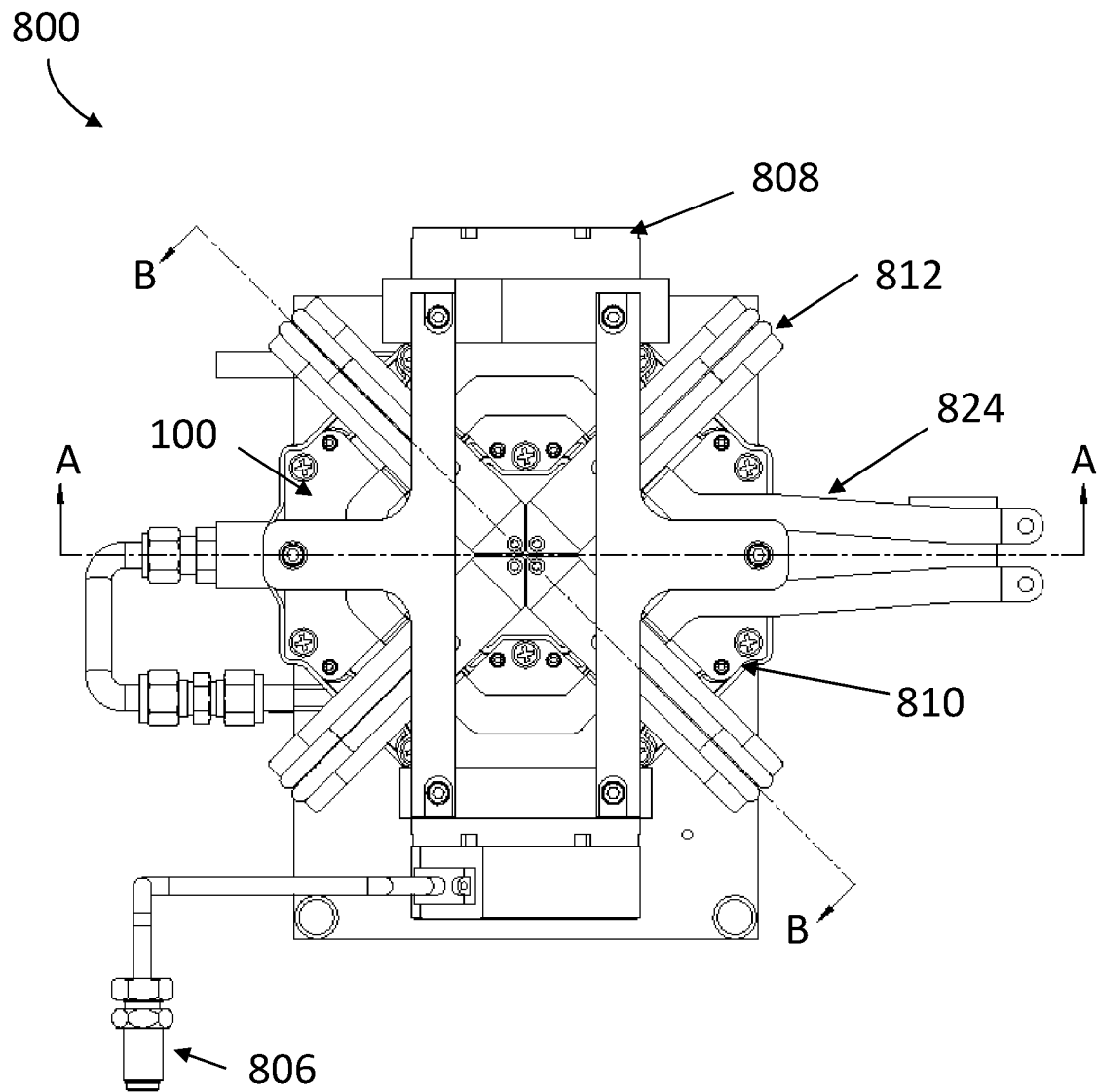
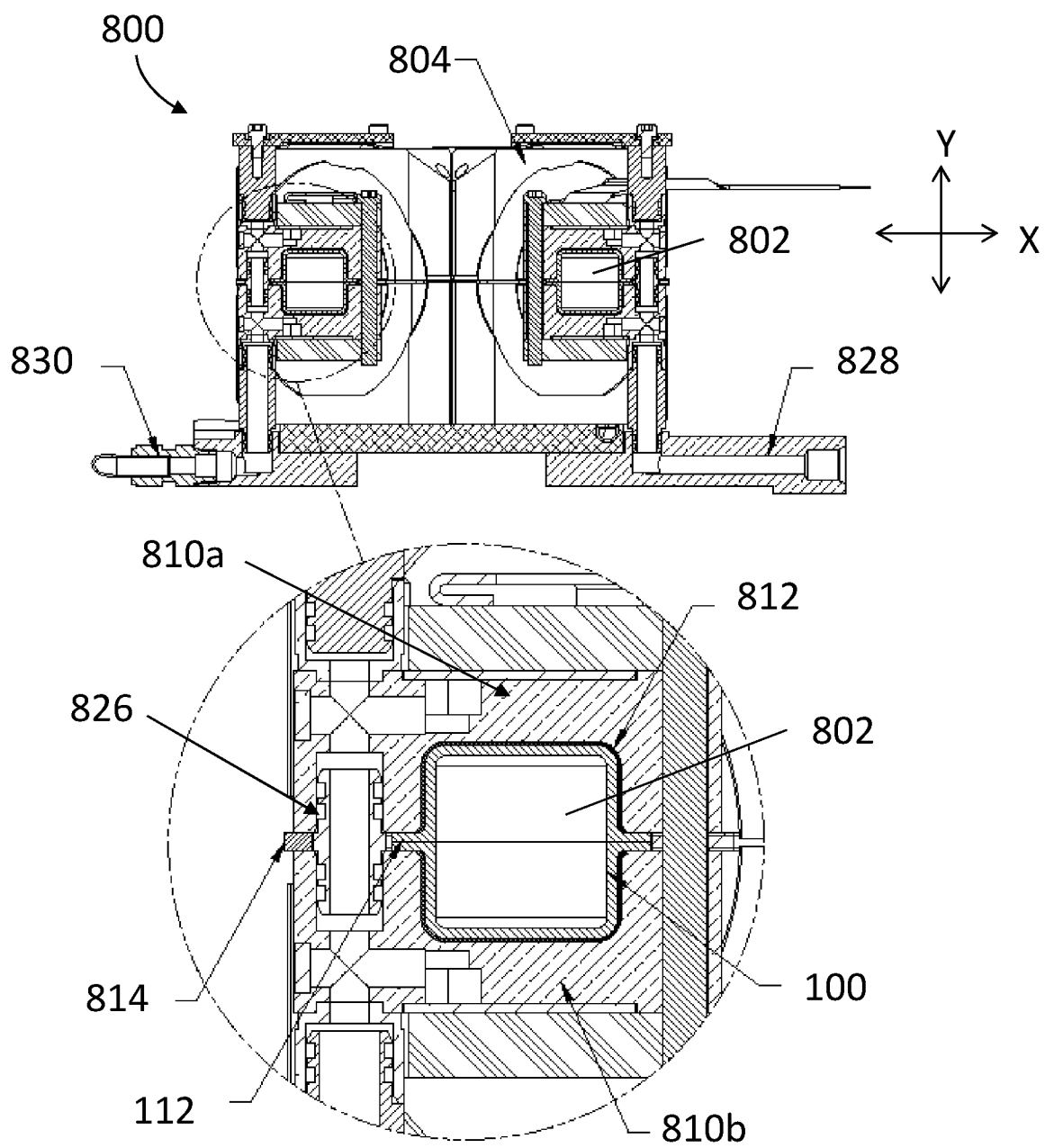
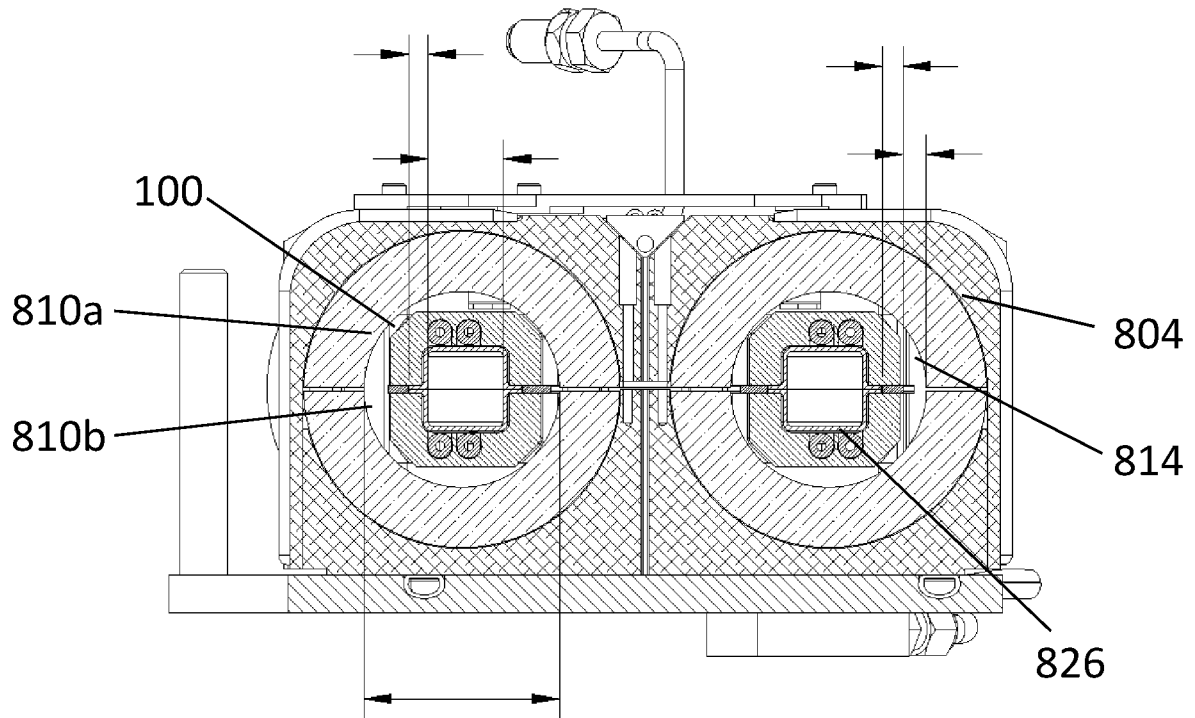


FIG. 8C



SECTION A-A

FIG. 9



SECTION B-B

FIG. 10

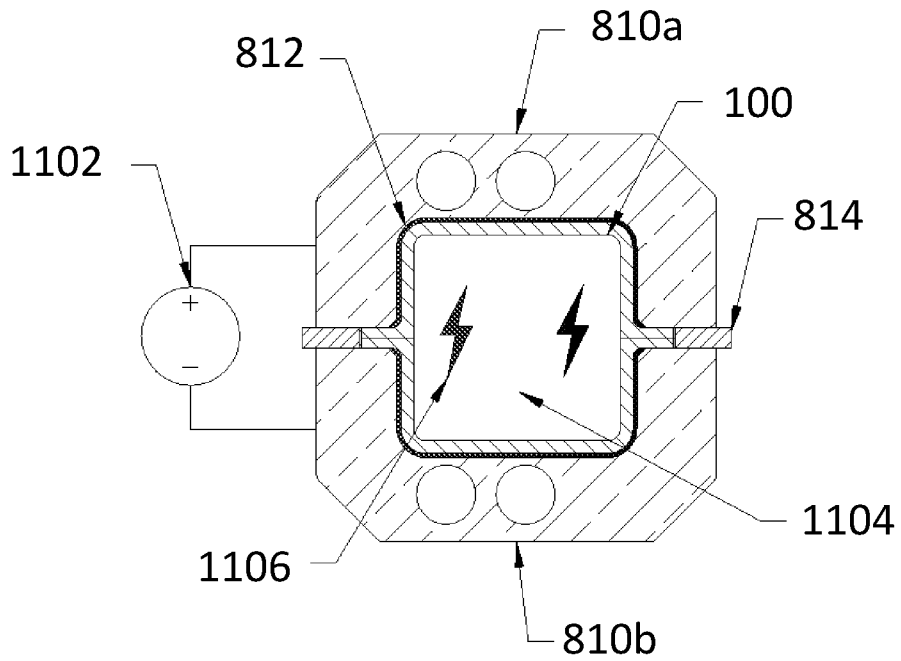
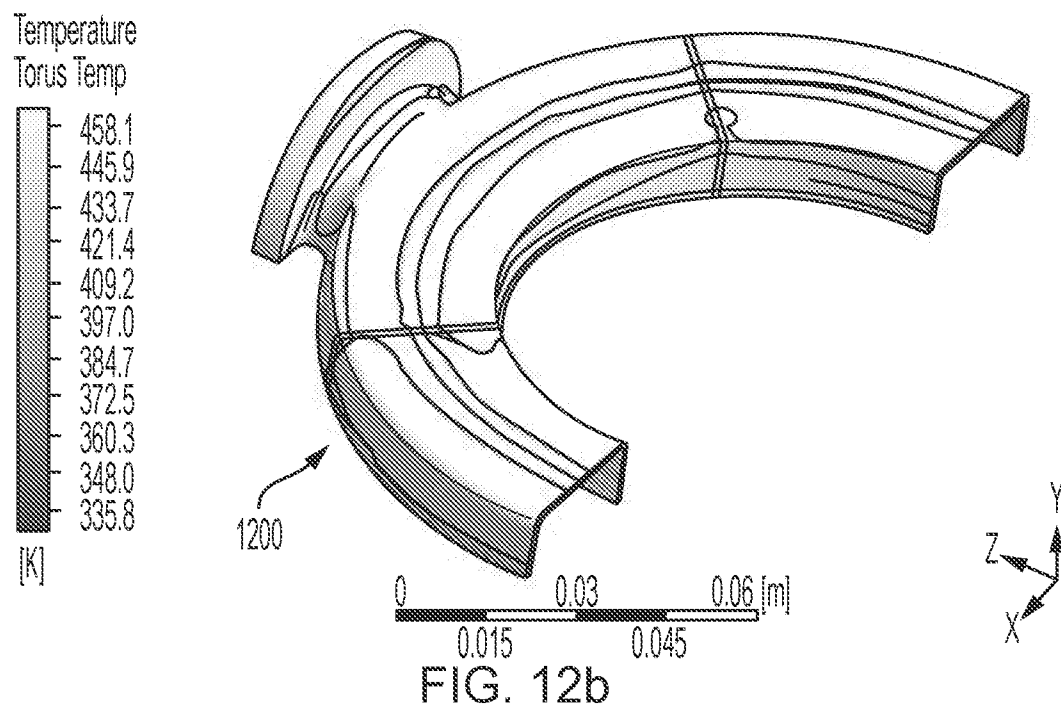
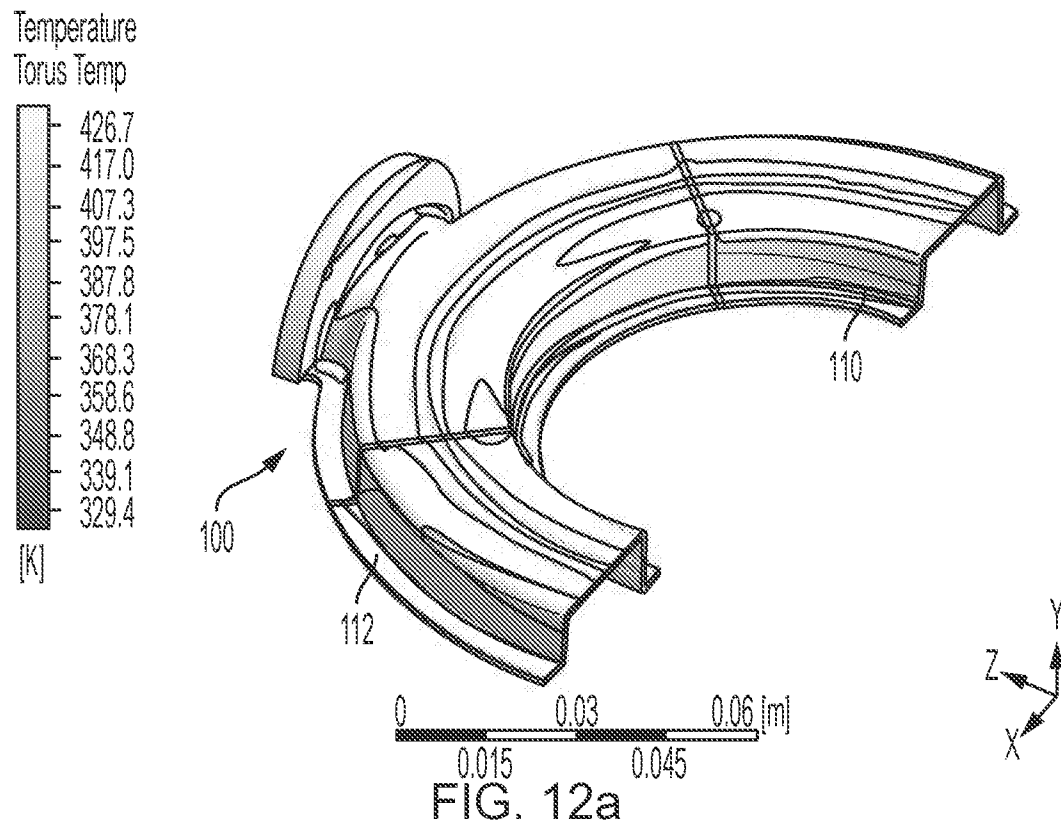


FIG. 11



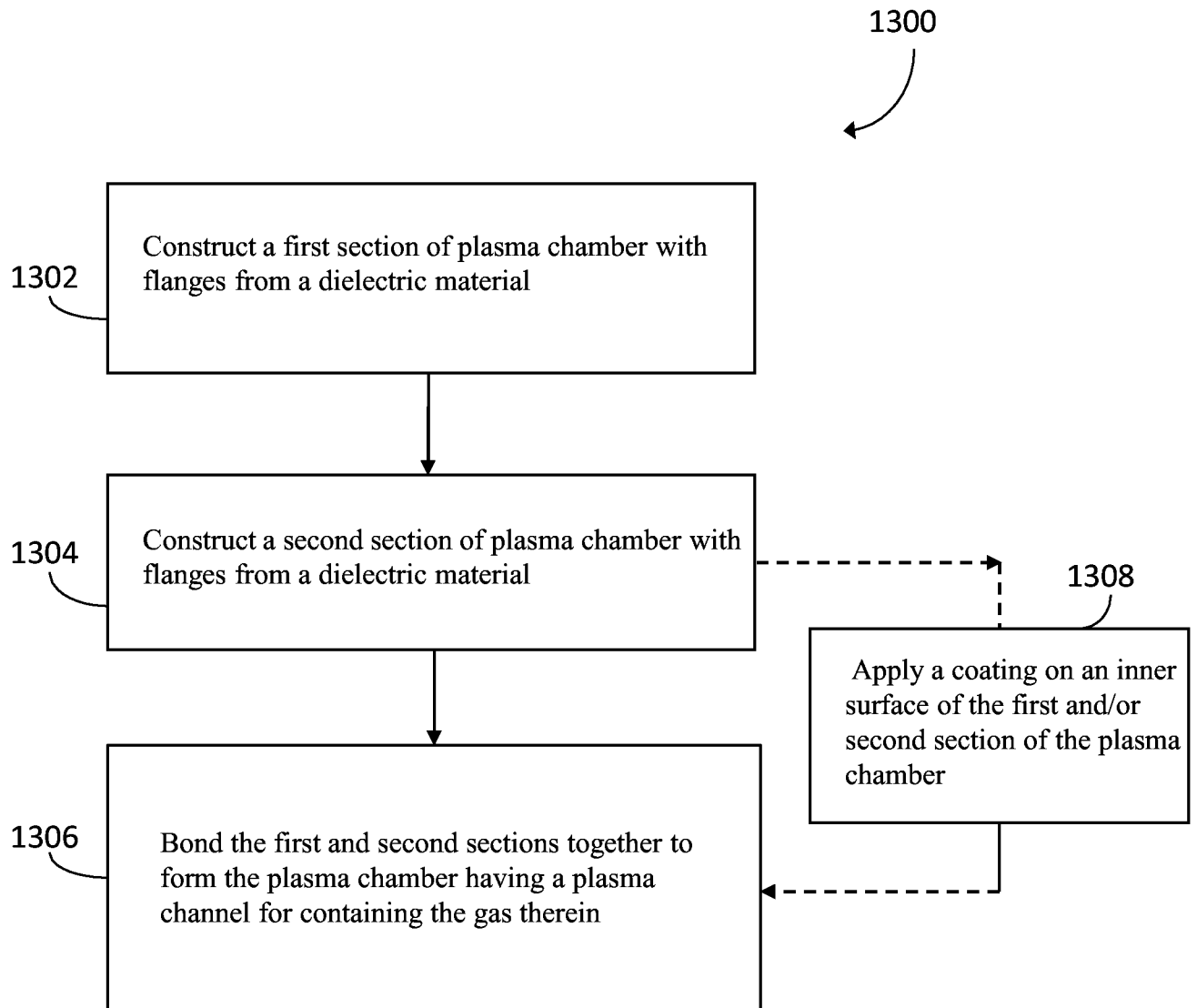


FIG. 13

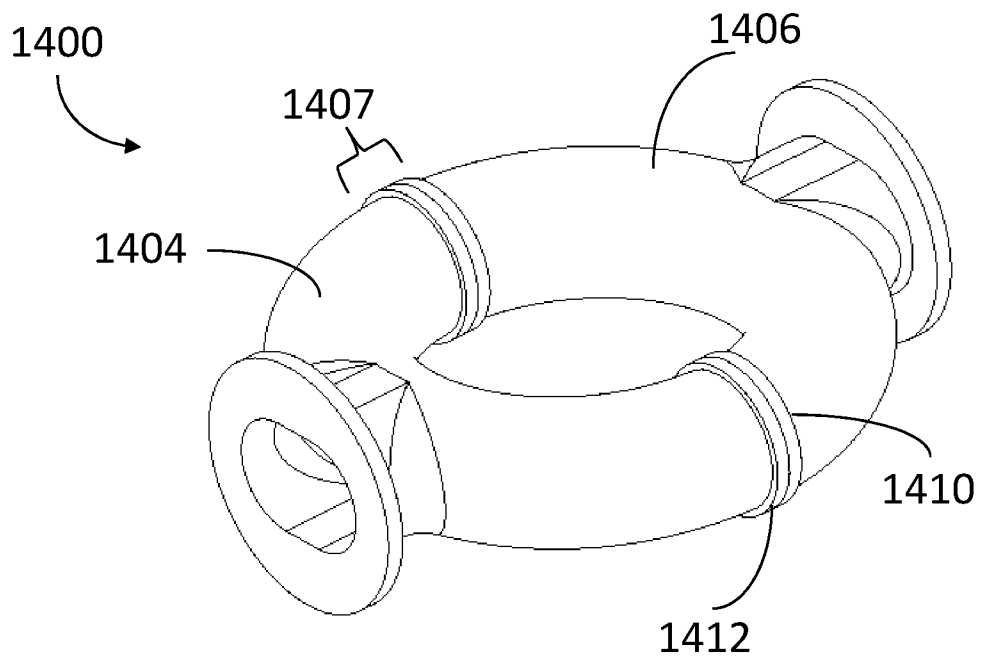


FIG. 14a

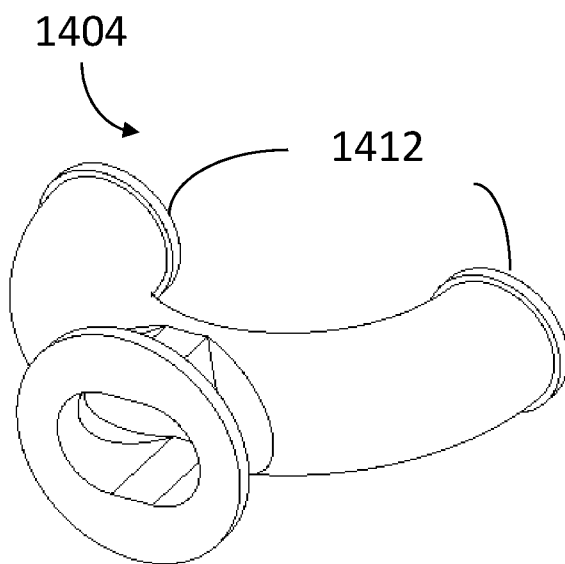


FIG. 14b

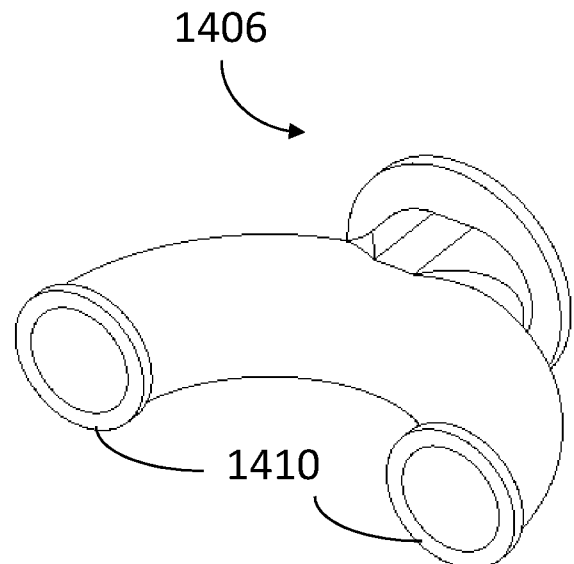
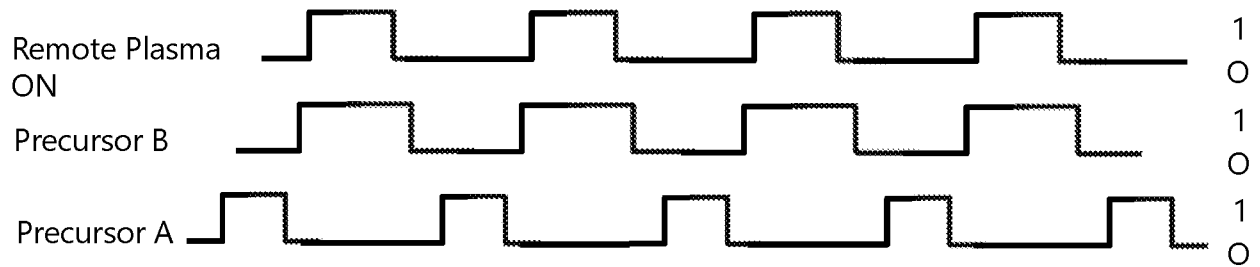
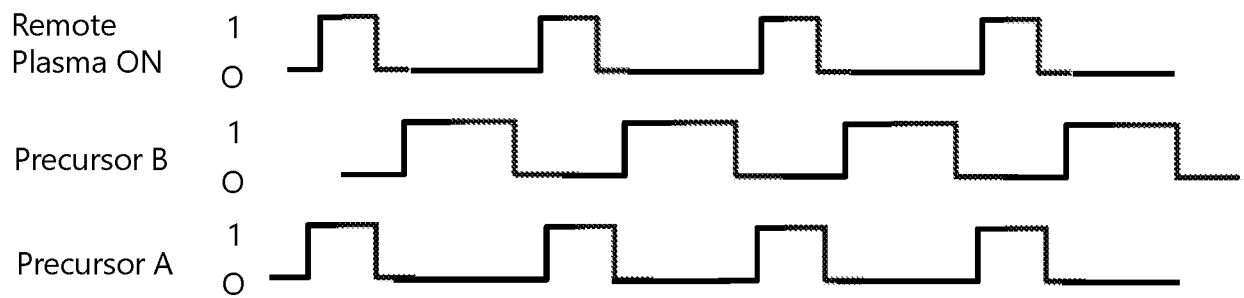
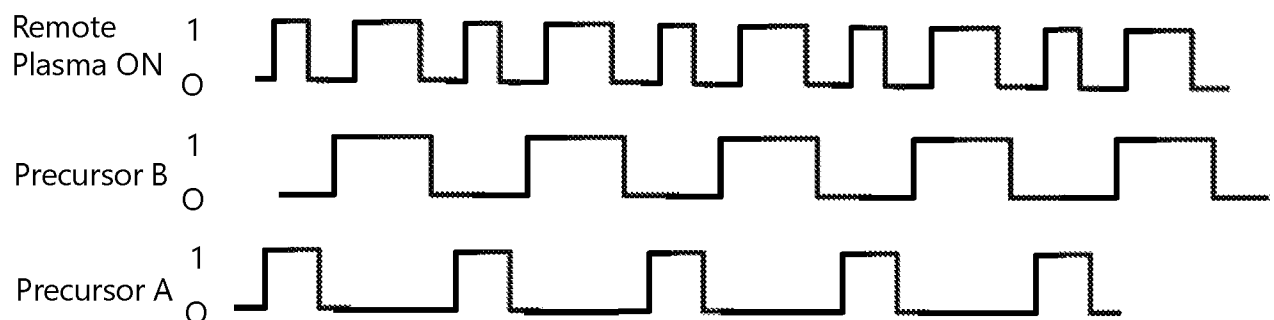


FIG. 14c

Pulsed Operation1 : Remote Plasma on for only Precursor B**FIG. 15a****Pulsed Operation2 : Remote Plasma on for Precursor A only****FIG. 15b****Pulsed Operation3 : Remote Plasma on for Both precursors****FIG. 15c**

Pulsed Operation4 : Remote Plasma on for Precursor B
with a Substrate Bias Applied with Precursor A

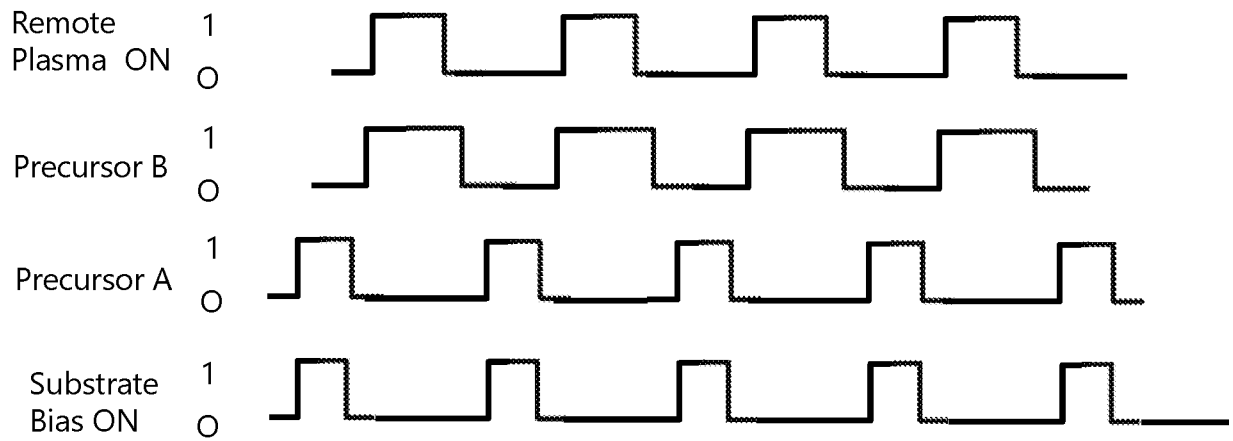


FIG. 15d